

Practitioner's Docket No.: MUH-12818

BOX AF

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Laurence A. GreenbergDecember 11, 2006  
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DEC 11 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No. 5871  
Filing Date : September 30, 2003  
Applicant : Ioannis Dotsikas  
Title : Method and Furnace for the Vapor Phase  
Deposition of Components onto  
Semiconductor Substrates with a Variable  
Main Flow Direction of the Process Gas  
TC/AU : 2818  
Examiner : Dung A. Le  
Customer No. : 24131

A M E N D M E N T under 37 CFR. § 1.116

Mail Stop **BOX AF** Amendment  
Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*OK to enter  
Dle 12/19/06*

S i r :

Responsive to the Office action dated August 11, 2006, kindly  
amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of  
claims, which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 9 of this paper.

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